

IN THE CLAIMS

The following is a complete listing of the claims, reflects all changes currently being made thereto, and replaces all earlier versions and listings.

1. (Currently Amended) A method for manufacturing an electron-emitting device, comprising:
 - a step for forming a solid-state insulating polymer film including a carbon atomic bond between a pair of electrodes formed on a substrate;
 - a step for heating said polymer film to change said polymer film into an electro-conductive film; and
 - a step for providing a potential difference between said pair of electrodes to energize electrically the electro-conductive film,

wherein the step for providing the potential difference is conducted after the step for heating said polymer film.

2. (Previously Presented) A method according to claim 1, wherein the step for heating includes a step for illuminating an electron beam onto at least a part of said polymer film.

3. (Previously Presented) A method according to claim 1, wherein the step for heating includes a step for illuminating light onto at least a part of said polymer film.

4. (Original) A method according to claim 3, wherein the light is light emitted from a xenon lamp as a light source.

5. (Original) A method according to claim 3, wherein the light is light emitted from a halogen lamp as a light source.

6. (Original) A method according to claim 3, wherein the light is a laser beam.

7. (Original) A method according to claim 1, wherein said polymer film is an aromatic polymer film.

8. (Original) A method according to claim 1, wherein the step for forming a polymer film utilizes an ink jet system.

9. - 15. (Canceled)

16. (Currently Amended) A method for manufacturing an electron-emitting device, comprising:

a step for forming a polymer film including a carbon atomic bond between a pair of electrodes formed on a substrate;

a step for illuminating an electron beam onto at least a part of said polymer film; and

a step for providing a potential difference between said pair of electrodes;

wherein the step for providing the potential difference is conducted after the step for illuminating the electron beam.

17. (Original) A method according to claim 16, wherein the step for illuminating the electron beam onto said polymer film includes a step for giving conductivity to at least a part of said polymer film.

18. (Original) A method according to claim 16, wherein the step for illuminating the electron beam onto said polymer film includes a step for reducing electrical resistance of said polymer film.

19. (Original) A method according to claim 16, wherein said polymer film is an aromatic polymer film.

20. (Original) A method according to claim 16, wherein the step for forming a polymer film utilizes an ink jet system.

21. (Currently Amended) A method for manufacturing an electron-emitting device, comprising:

- a step for forming a polymer film including a carbon atomic bond between a pair of electrodes formed on a substrate;
- a step for illuminating light onto at least a part of said polymer film;
- and
- a step for providing a potential difference between said pair of electrodes,

wherein the step for providing the potential difference is conducted after the step for illuminating light.

22. (Original) A method according to claim 21, wherein the step for illuminating light onto said polymer film includes a step for giving conductivity to at least a part of said polymer film.

23. (Original) A method according to claim 21, wherein the step for illuminating light onto said polymer film includes a step for reducing electrical resistance of said polymer film.

24. (Original) A method according to claim 23, wherein the light is light emitted from a xenon lamp as a light source.

25. (Original) A method according to claim 23, wherein the light is light emitted from a halogen lamp as a light source.

26. (Original) A method according to claim 23, wherein the light is a laser beam.

27. (Original) A method according to claim 21, wherein said polymer film is an aromatic polymer film.

28. (Original) A method according to claim 21, wherein the step for forming a polymer film utilizes an ink jet system.

29. (Currently Amended) A method for manufacturing an electron source having a plurality of electron-emitting devices, wherein:
each electron-emitting device is manufactured in accordance with the method according to ~~any one of claims~~ claim 1 [[to 28]].

30. (Original) A method for manufacturing an image-forming apparatus having an electron source including a plurality of electron-emitting devices, and an image-forming member for forming an image by illumination of electron emitted from said electron source, wherein:

said electron source is manufactured by a method according to claim

29.

31. - 32. (Canceled)

33. (New) A method for manufacturing an electron source having a plurality of electron-emitting devices, wherein

each electron-emitting device is manufactured in accordance with the method according to 16.

34. (New) A method for manufacturing an image-forming apparatus having an electron source including a plurality of electron-emitting devices, and an image-forming member for forming an image by illumination of electron emitted from said electron source, wherein

said electron source is manufactured by a method according to claim

33.

35. (New) A method for manufacturing an electron source having a plurality of electron-emitting devices, wherein

each electron-emitting device is manufactured in accordance with the method according to 21.

36. (New) A method for manufacturing an image-forming apparatus having an electron source including a plurality of electron-emitting devices, and an image-forming member for forming an image by illumination of electron emitted from said electron source, wherein

said electron source is manufactured by a method according to claim

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